

IN THE CLAIMS

Please amend the claims as follows:

Claim 1 (Currently Amended): A wafer processing apparatus for processing a wafer transferred from a clean box including an access opening to allow for accessing an inside of the clean box and a lid to close the access opening, wherein the inside of the clean box is separated from a circumstance of the outside of the clean box by closing the access opening with a lid, said wafer processing apparatus comprising:

a chamber;

a first opening through which gas fluidically communicates between an interior and an exterior of the chamber formed on a wall of said chamber, said first opening allowing for accessing the inside of the clean box when the clean box is placed beside the chamber so that the access opening confronts said first opening; and

a door including a door body whose outer shape is smaller than an inner shape of said first opening so as to close said first opening and at least one projection extending from the door body member capable of holding the lid of the clean box so as to open or close the access opening and said first opening from an inside of said chamber, said door member having an edge portion and another edge portion,

wherein in a condition where [[the]] said door is positioned to close the member closes said first opening, the projection edge portion contacts with a peripheral portion of said first opening an inside [[a]] wall of said chamber to overlap a peripheral portion of said first opening[[.]] and said another edge portion forms an aperture which defined by an edge of said first opening and said another edge portion of said door member, the inside of said chamber gas fluidically communicates between the interior and the exterior communicating with the outside of [[the]] said chamber through the aperture, still remains between the outer shape of the door body and the inner shape of said first opening.

Claim 2 (Currently Amended): A wafer processing apparatus according to claim 1, wherein the edge portion is a projection is provided at each corners of the door body.

Claims 3-4 (Canceled).

Claim 5 (Currently Amended): A wafer processing apparatus according to claim [[4]] 2, wherein the projection is provided at each corners of the door to protrude protrudes toward the outside of the door.

Claim 6 (Canceled).

Claim 7 (Currently Amended): A wafer processing apparatus according to claim 1: wherein the projection and the aperture effect effects suppressing an influence on a gas flow passing through a communication path from the interior inside to the exterior outside of the chamber in a case of comparing a case that there is no projection.

Claim 8 (Previously Presented): A wafer processing apparatus according to claim 7, wherein the influence is a gas flow turbulence generated when the door opens or closes.

Claims 9-10 (Canceled).

Claim 11 (New): A wafer processing apparatus for processing a wafer transferred from a clean box including an access opening to allow for accessing an inside of the clean

box and a lid to close the access opening, wherein the inside of the clean box is separated from a circumstance of the outside of the clean box by closing the access opening with a lid, said wafer processing apparatus comprising:

a chamber;

a first opening formed on a wall of said chamber, said first opening allowing for accessing the inside of the clean box when the clean box is placed beside the chamber so that the access opening confronts said first opening; and

a door member capable of holding the lid of the clean box so as to open or close the access opening and said first opening from an inside of said chamber,

wherein an outer shape of said door member is larger than a periphery of said first opening to cover a whole part of said first opening from the inside of said chamber, and

wherein in a condition where said door member closes said first opening, said door member has a through aperture to gas fluidically communicate between the inside and the outside of said chamber through the aperture within an area in the outer shape of said door member.